

DO NOT ENTER: /SM/

02/11/2009

RECEIVED
CENTRAL FAX CENTER
JAN 23 2009

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: OZAKI, Takashi, et al.

Group Art Unit: 1792

Serial No.: 10/528,137

Examiner: NIACARTHUR, Sylvia

Filed: December 12, 2005

P.T.O. Confirmation No.: 2307

FOR: SUBSTRATE PROCESSING APPARATUS AND METHOD FOR
MANUFACTURING A SEMICONDUCTOR DEVICE**RESPONSE UNDER 37 CFR §1.116**
- EXPEDITED RESPONSE -
GROUP ART UNIT 1792**MAILSTOP AF**Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

January 23, 2009

Sir:

In response to the Final Office Action dated October 2, 2008, extended from January 2, 2009 to February 2, 2009 by a one (1) month Petition for Extension of Time, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 9 of this paper.